

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Rosengaus et al.

Attorney Docket No.: KLA1P001C1

Application No.: 09/474,941

Examiner: Rosenberger, R.

Filed: December 30, 1999

Group: 2877

Title: SYSTEM AND METHOD FOR  
INSPECTING SEMICONDUCTOR WAFERS

## CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Commissioner for Patents, Washington, DC 20231 on January 8, 2003.

Signed: 

Tara Hayden

AMENDMENT TRANSMITTALCommissioner for Patents  
Washington, DC 20231

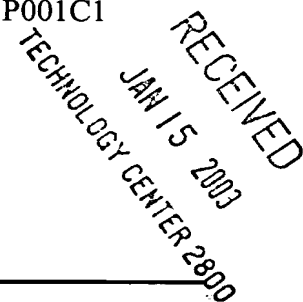
Sir:

Transmitted herewith is an Amendment in the above-identified application.

The fee has been calculated as shown below.

	Claims After Amendment		Highest Previously Paid For	Present Extra	Small Entity Rate Fee	Large Entity Rate Fee
Total Claims	16	MINUS	32	00	x 9 =	x 18 = 00
Independent Claims	05	MINUS	07	00	x 42 =	x 84 = 00
Multiple Dependent Claim Present and Fee Not Previously Paid					\$140.00	\$280.00
Total					\$	\$

- ☒ Applicant(s) hereby petition for a one month extension(s) of time to respond to the aforementioned Office Action.
- ☐ Applicant(s) believe that no (additional) Extension of Time is required; however, if it is determined that such an extension is required, Applicant(s) hereby petition that such an extension be granted and authorize the Commissioner to charge the required fees for an Extension of Time under 37 CFR 1.136 to Deposit Account No. 500388.
- ☒ Enclosed is our Check No. 6756 in the amount of \$110.00 to cover the additional claim fee and/or extension of time fees.
- ☒ Please charge the required fees, or any additional fees required to facilitate filing the enclosed response, to Deposit Account No. 500388 (Order No. KLA1P001C1).

Respectfully submitted,  
BEYER WEAVER & THOMAS, LLPPhillip P. Lee  
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PATENT

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Title: A SYSTEM AND METHOD FOR  
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I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Assistant Commissioner for Patents, Washington, DC 20231 on January 8, 2003.

Printed Name: Tara Hayden

Signed: AMENDMENT F

Assistant Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

In response to the Office Action dated 11 September 2002, please amend the above-identified patent application and consider the remarks as follows. An one-month extension of time is herein requested.

IN THE CLAIMS:

Please REWRITE claims 59, 61-63 and 65 as follows:

59. (Amended Once) A semiconductor manufacturing system comprising:
- a wafer handling chamber having a plurality of facets, the wafer handling chamber containing a vacuum environment;
  - a plurality of wafer processing tools, each of the tools being attached to a respective facet on the wafer handling chamber;
  - a first metrology tool attached to one of the facets of the wafer handling chamber, wherein the first metrology tool measures critical dimensions on pattern-etched semiconductor